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WHAT IS CLAIMED IS:

- 1. A composition for sealing a semiconductor device having thermoplastic properties and a line expansion coefficient of 6.0 \times 10⁻⁵[1/°C] or less at a temperature of 80°C to 130°C.
- 2. A composition for sealing a semiconductor device according to claim 1, wherein the line expansion coefficient 4.75×10^{-5} [1/°C] or less at a temperature of 150° C to 200° C.
- 3. A composition for sealing a semiconductor device according to claim 1, wherein a line expansion coefficient ratio between a flow direction and a normal direction of the flow direction is 0.55 or more.
- 4. A composition for sealing a semiconductor device according to claim 1, wherein the composition has a bending strength after solidification is 74 MPa or more.
- 5. A composition for sealing a semiconductor device according to claim 1, wherein an adhesion imparting agent is added to improve adhesion properties to another material by binding with a polar group.
- 6. A composition for sealing a semiconductor device according to claim 1, further containing silica particles.
- 7. A composition for sealing a semiconductor device according to claim 1, further containing a fibrous material.

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- 8. A composition for sealing a semiconductor device according to claim 1, further containing a thermosetting resin material.
- 9. A composition for sealing a semiconductor device according to claim 1, wherein a product obtained by multiplying a value of a line expansion at 25 to 80° C plus a line expansion at $80-125^{\circ}$ C after solidification, by a bending strength is 25 MPa or less.
 - 10. A semiconductor device comprising:
 a semiconductor element;
- a semiconductor resin composition for sealing the semiconductor element; and

a conducting material electrically connected to the semiconductor element one end of which is sealed with the semiconductor resin composition,

wherein the semiconductor sealing resin composition has thermoplastic properties and a thermal expansion coefficient is 6.0 \times 10⁻⁵[1/°C] or less at a temperature of 80 to 130°C.

- 11. A semiconductor device according to claim 10, wherein the semiconductor sealing resin composition has thermoplastic properties and a thermal expansion coefficient at 150 to 200° C is 4.75×10^{-5} [1/°C] or less.
- 25 12. A semiconductor device according to claim 10, wherein the semiconductor sealing resin composition has thermoplastic properties and a line expansion

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coefficient ratio between a flow direction and a normal direction of the flow direction is 0.55 or more.

- 13. A semiconductor device according to claim 10, wherein a bending strength of the semiconductor sealing resin composition after solidification is 74 MPa or more.
- 14. A semiconductor device according to claim 10, wherein an adhesion imparting agent is added the semiconductor sealing resin composition to improve adhesion properties to another material by binding with a polar group.
- 15. A semiconductor device according to claim 10, wherein the semiconductor sealing resin composition contains silica particles.
- 16. A semiconductor device according to claim 10, wherein the semiconductor sealing resin composition contains a fibrous material.
 - 17. A semiconductor device according to claim 10, wherein the semiconductor sealing resin composition contains a thermosetting material.
 - 18. A semiconductor device according to claim 10, wherein the semiconductor element is coated with polyimide.
- 19. A semiconductor device according to claims 10 to 13, wherein the semiconductor sealing resin composition is thermoplastic and a product obtained by multiplying a value of a line expansion at 25 to 80° C

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plus a line expansion at $80-125^{\circ}$ C after solidification, by a bending strength is 25 MPa or less.

- 20. A method of manufacturing a semiconductor device comprising the steps of:
- electrically connecting a semiconductor element and a conducting material; and

sealing the semiconductor element with a thermoplastic semiconductor sealing resin composition and a line expansion coefficient at 80 to 130°C is 6.0×10^{-5} [1/°C] or less.